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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re application of: Fair et al.

Attorney Docket No.:  
NOVLP067D2/NVLS-000376D2

Application No.: NEW

Examiner: UNASSIGNED

Filed: HEREWITH

Group: UNASSIGNED

Title: SEQUENTIAL ELECTRON INDUCED  
CHEMICAL VAPOR DEPOSITION

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**PRELIMINARY AMENDMENT**

Mail Stop Patent Application  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Before examination on its merits, please amend the above-identified patent application as follows:

**Amendments to the Specification** begin on page 3 of this paper.

**Remarks/Arguments** begin on page 3 of this paper.